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FIG.1

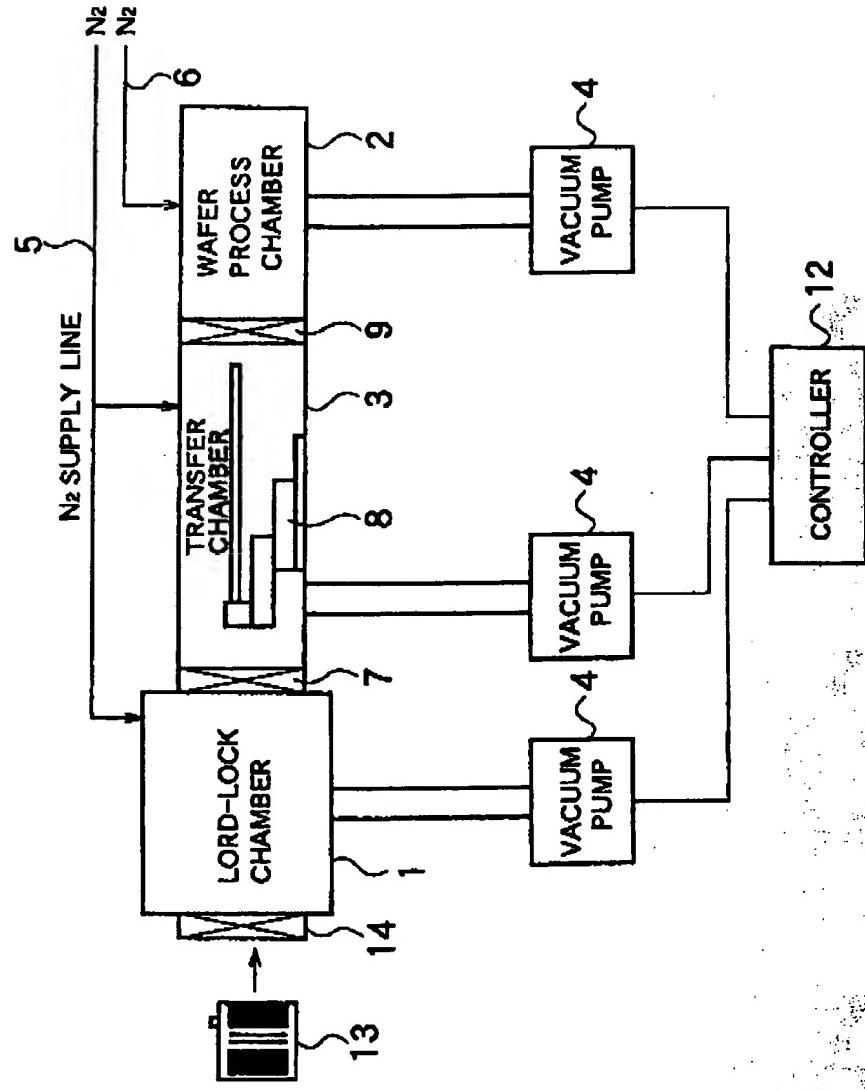


FIG.2

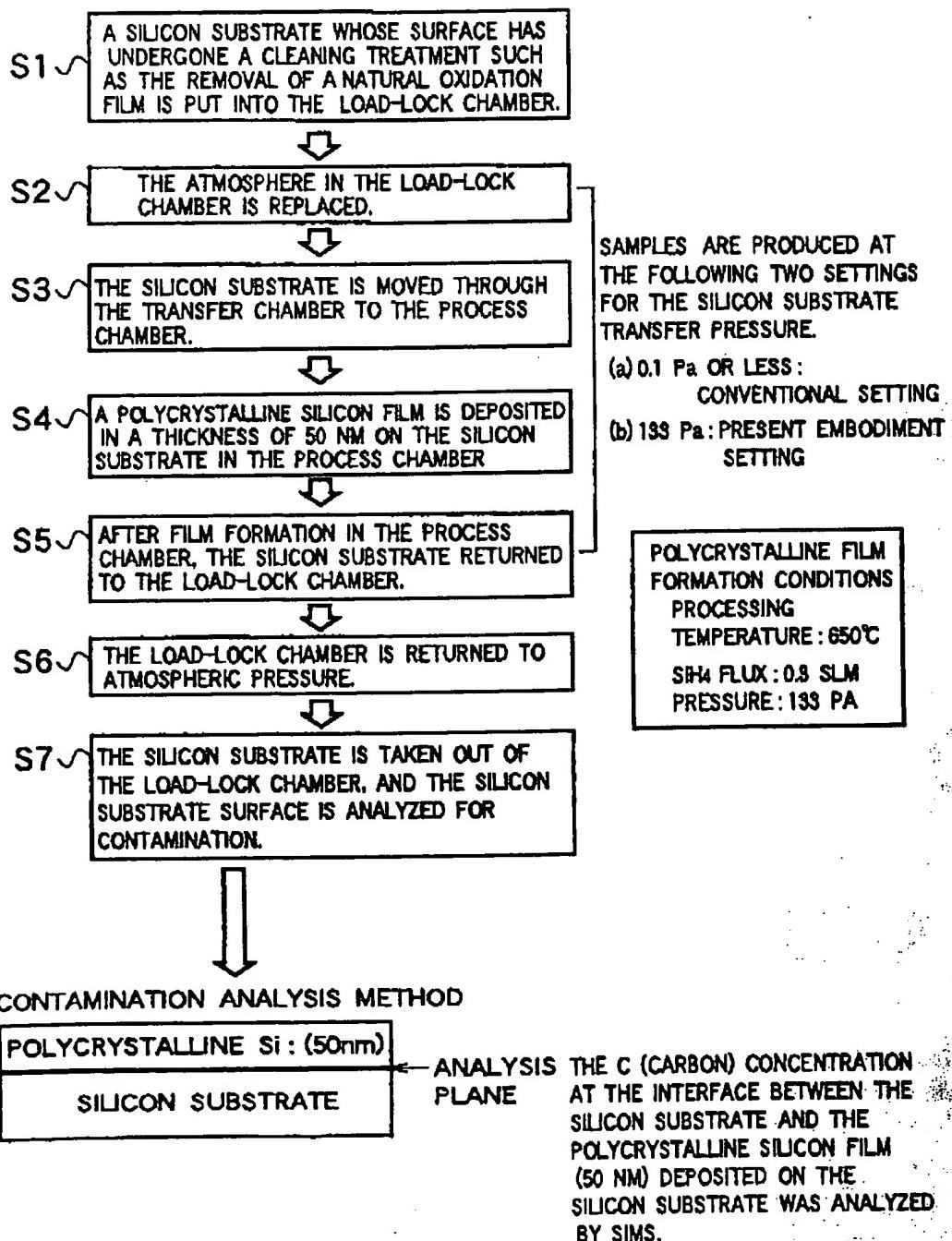


FIG.3

SUBSTRATE TRANSFER PRESSURE		CARBON CONCENTRATION (atoms/cm ²)
(A) CONVENTIONAL SETTING	ATTAINABLE VACUUM TRANSFER 0.1Pa OR LESS	1.90×10^{14}
(B) PRESENT EMBODIMENT SETTING	183Pa	3.70×10^{13}

5.0×10^{12} atoms/cm²
(BEST DATA)

FIG.4

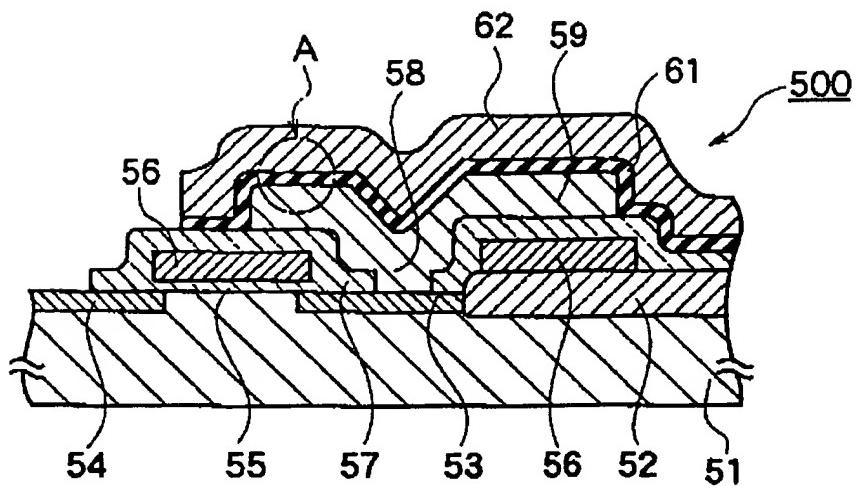


FIG.5

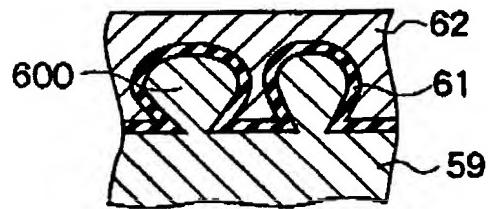


FIG.6

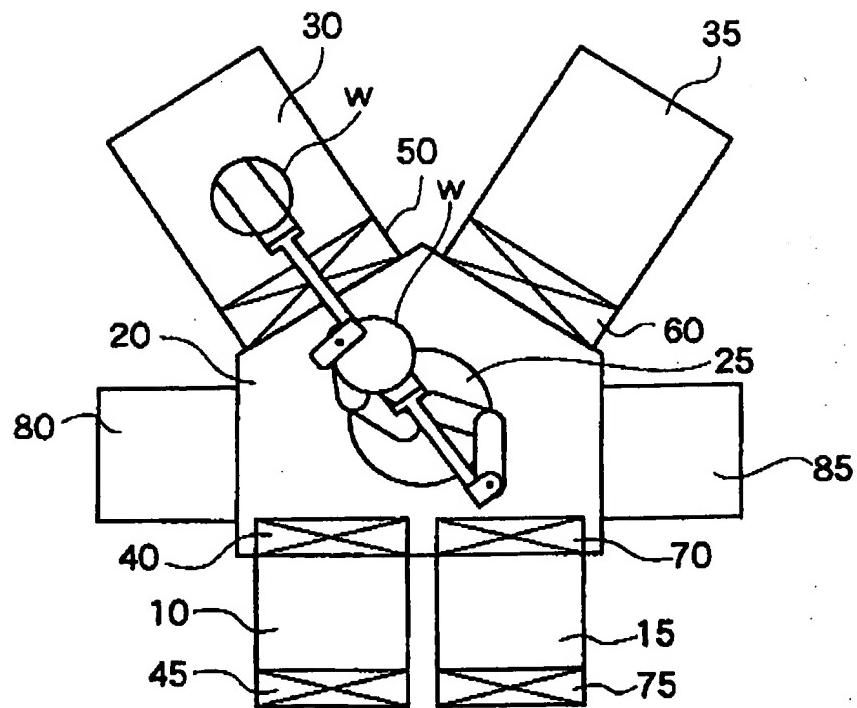


FIG.7

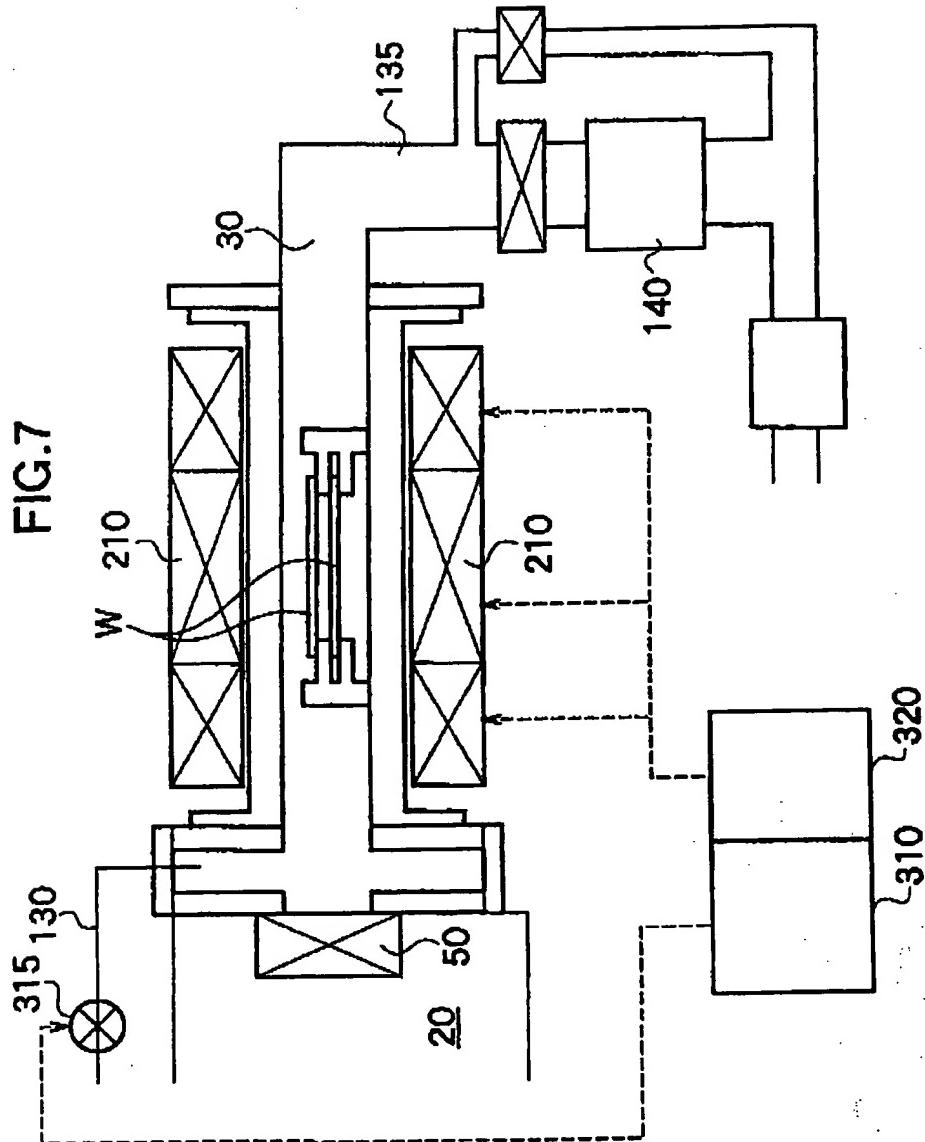
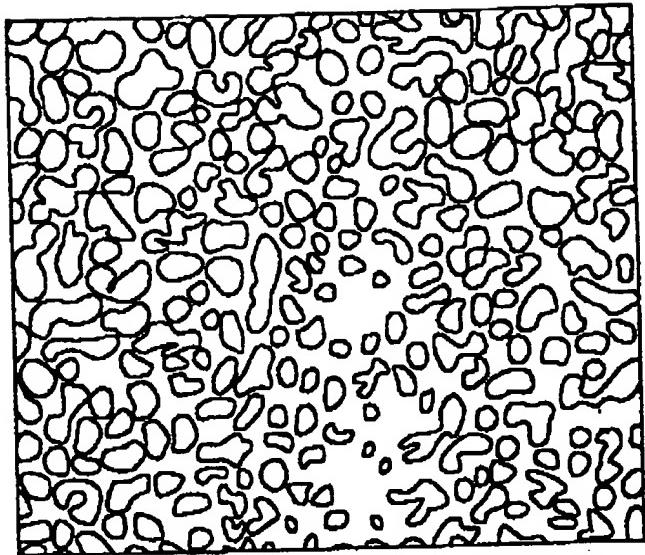
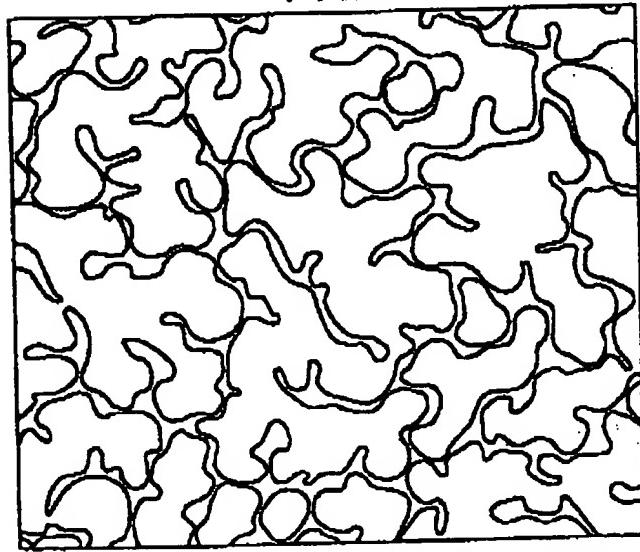


FIG.8



WITH ATTAINABLE VACUUM TRANSFER
INADEQUATE HSG FORMATION
(LACK OF SURFACE BUMPINESS)
DUE TO CONTAMINATION OF
WAFER SURFACE

FIG.9



WITH NITROGEN GAS SUPPLY: 0.5 slm, 50 Pa
ADEQUATE HSG FORMATION (VERY BUMPY SURFACE)